고밀도 산소 플라즈마 처리된 폴리머 기판에 성장시킨 CdS 박막의 특성 분석

송우창, 박승범, 임동건, 이재형*, 박종국**, 박하용**, 김정호*** 충주대학교, 군산대학교*, 강원대학교**, Kyushu Institute of Technology***

Structural Properties of chemically deposited CdS Films on plasma treated PET

Woochang Song, Seungbeom Park, Donggun Lim, Jaehyeong Lee, Jongkuk Park, Hayong Park and Jeongho Kim Chungju National Univ., Kunsan National Univ., Kangwon National Univ. and Kyushu Institute of Technology.

Abstract: CdS is II-VI semiconductor with a wide band gap of approximately 2.42 eV. CdS is the most popularly employed heterojunction partner to p-CdTe due to its similar chemical properties. In this work, to improvement of the surface properties of the CdS films, PET substrate is treated by high density O₂ plasma. CdS films are prepared by chemical bath deposition(CBD) method. In case of the PET substrate with plasma treatment for 2min, the crystalline orientation of CdS films exhibits a strong hexagonal(002). Grain size was increased from 300nm without O₂ plasma treatment to 380nm with an O₂ plasma treatment.

Key Words: CdS, ICP, PET, CBD